

Docket No.: 1592-0168PUS1  
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

---

In re Patent Application of:  
Naoharu NAKAISO

Application No.: 10/549,933

Confirmation No.: 7899

Filed: September 11, 2006

Art Unit: 1792

---

For: SUBSTRATE PROCESSING  
APPARATUS AND SEMICONDUCTOR  
DEVICE PRODUCING METHOD

---

Examiner: R. N. Kackar

**Amendment After Final Action Under 37 C.F.R. 1.116**

MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Please don't enter

Sir:

/RK/

**INTRODUCTORY COMMENTS**

In response to the Office Action dated March 18, 2008, finally rejecting claims 1-4 and 8-20, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page of this paper.

**Remarks/Arguments** begin on page 7 of this paper.